

## **INSPECTION METHOD AND DEVICE MANUFACTURING METHOD**

### **ABSTRACT OF THE DISCLOSURE**

A method according to one embodiment of the invention may be  
5 applied to enhance scatterometry measurements made from a two-component  
test pattern. Reference patterns corresponding to each of the components of  
the two-component pattern are also printed. Scatterometry signals derived  
from the reference patterns, corresponding to the separate components of the  
test pattern, are used to enhance the signal from the test pattern to improve  
10 sensitivity and signal-to-noise ratios.